

Sensitive element of a pseudospin-valve type sensor device has the form of a parallelepiped consisting of a substrate and sequentially arranged: a lower hard magnetic film layer, a non-magnetic film spacer, a soft magnetic film layer, and an upper hard magnetic film layer. An additional second non-magnetic spacer is located between the soft magnetic film layer and the upper hard magnetic film layer. Wherein, the substrate is made of polished glass 2 mm thick, the lower and upper hard magnetic film layers are made of Co 25 nm, the first and second non-magnetic spacers are made of Cu 5 nm film, and the soft magnetic layer is made of $\text{Fe}_{0,5}\text{Ni}_{0,5}$ 25 nm film.